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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

CONFIRMATION NO. 3236

Applicant : Takayuki TOSHIMA, et al.  
Serial No. : 10/052,534 Art Unit : 1746  
Filed : January 23, 2002 Examiner : Michail KORNAKOV  
For : Substrate Processing Apparatus and Substrate Processing Method

**RESPONSE TO RESTRICTION REQUIREMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir :

A response to the Office Action mailed July 2, 2004 is due by August 2, 2004. The Action required restriction between

Group I of claims 1-19, drawn to a substrate processing apparatus, and

Group II of claims 20-34, drawn to a substrate processing method.

Applicants hereby elect Group I of claims 1-19, drawn to a substrate processing apparatus, for prosecution in this application.

Applicants reserve the right to file divisional application(s) for the non-elected claims in due course. In addition, Applicants advise that no change in the inventorship of the application is needed.

Applicants submit that this application now is in condition for examination on the merits and early action in that regard is solicited.

Respectfully submitted,

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